

### March 30, 2003, Sunday Tutorials

Location:	Room: Landmark A	Room: Landmark B	Room: Landmark C	
<b>8:00–9:30 a.m.</b>	111: An Introduction to Semiconductor Reliability— Vijay Reddy, TI	121: ESD Basics— Charvaka Duvvury, TI		
<b>10:00–11:30 a.m.</b>		122: ESD Testing and Failure Analysis for Semiconductor IC's— Jonathan Brodsky, TI		
<b>Lunch Break</b>				
<b>1:30–3:00 p.m.</b>	112: Introduction to Predictive WLR—Eric Snyder, Sandia Technologies	123: ESD High Current Phenomena, Modeling and Process Effects— Gianluca Boselli, TI	131: Problems & Solutions for FA on Advanced Microelectronic Circuits— Chris Henderson, Sandia Nat'l Labs	
<b>3:30–5:00 p.m.</b>		124: Advanced ESD Protection Design— Charvaka Duvvury, TI	132: Optical Tools for IC Failure Analysis — Ed Cole, Jr., Sandia Nat'l Labs	

### March 31, 2003, Monday Tutorials

Location:	Room: Landmark A	Room: Landmark B	Room: Landmark C	Room: Landmark D
<b>8:00–9:30 a.m.</b>	211: Reliable Plastic Encapsulated Microcircuits for Harsh Environments— Chuck Reusnow Lockheed Martin Missiles & Fire Control	221: Dielectric Rel Models & Mechanisms — Paul Nicollian TI	231: Integration Challenges of Cu Low k Integration — Glenn Alers, Novellus	
<b>10:00–11:30 a.m.</b>	and Brian Russell, Dow Corning	222: Physics of soft-breakdown and implications for ICs Ashraf Alam, Bell Labs	232: Current Challenges of Cu Electromigration Reliability— Christine S. Hau-Riege, AMD	241: NBTI challenges in PMOSFETs of Advanced CMOS Technologies—Guiseppe La Rosa, IBM Microelectronics
<b>Lunch Break</b>				
<b>1:30–3:00 p.m.</b>	212: Reinventing CMOS: Physics, Reliability and The Roadmap— Ted Dellin, SNL	223: Ultra thin oxide reliability in CMOS devices & circuits— Jim Stathis, IBM	233: Impact of Low k on EM Reliability for Cu Interconnects— Paul Ho, U.T. Austin	242: SER Program—Daniel Chesire 1. Robert Baumann, TI 2. Steve Wender, Los Alamos 3. Fred Sexton & Paul Dodd, Sandia 4. Mike Tucker, Alpha Sciences 5. Charles Slayman, Sun Microsyst.
<b>3:30–5:00 p.m.</b>		224: Issues in high k rel— Robin Degraeve, IMEC	234: Interfacial Adhesion and its Impact on Cu Interconnect Reliability—Michael Lane, IBM	